

**REMARKS/ARGUMENTS**

Restriction to one of the following inventions is required under 35  
U.S.C.121:


- 5 I. Claims 1-9, drawn to a process for depositing silicon nitride films,  
classified in class 427, subclass 248.1.
- II. Claims 10-15, drawn to an apparatus for depositing silicon nitride films,  
classified in class 118, subclass 715.

**Response:**

- The applicant has consequently amended the claims in the above
- 10 AMENDMENTS TO THE CLAIMS section to elect claims 1-9 in invention I relating to  
a process of depositing silicon nitride films to be examined in the present application.  
Claims 10-15 are non-elected and therefore canceled.

- Applicant respectfully requests that a timely Notice of Allowance be issued in
- 15 this case.

Sincerely yours,



Date: 06/01/2007

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D.C. is 12 hours behind the Taiwan time, i.e. 9 AM in D.C. = 9 PM in Taiwan.)